

(Use several sheets if necessary)

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Application Number

Applicant(s)

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Filing Date

Group Art Unit

unknown

U.S. PATENT DOCUMENTS

j11046 U.S. PTO
 09/944795
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FOREIGN PATENT DOCUMENTS

Translation	
YES	NO

OTHER DOCUMENTS *(Including Author, Title, Date, Pertinent Pages, Etc.)*

NEW PHASE SHIFT GRATINGS FOR MEASURING ABERRATIONS, by Hiroshi Nomura, published by SPIE, dated February 27, 2001 (11 pages)

EXAMINER

DATE CONSIDERED

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